List of Publications by Year in descending order

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#	Article	IF	CITATIONS
1	Shadow moire´ profilometry using the phase-shifting method. Optical Engineering, 2000, 39, 2119.	1.0	55
2	Measurement of Dispersion of Effective Electro-Optic Coefficients r <sub>13</sub> <sup>E</sup> and r <sub>33</sub> <sup>E</sup> of Non-Doped Congruent LiNbO <sub>3</sub> Crystal. Japanese Journal of Applied Physics, 2008, 47, 5503.	1.5	28
3	Si/SiO2 Core/Shell Luminescent Silicon Nanocrystals and Porous Silicon Powders With High Quantum Yield, Long Lifetime, and Good Stability. Frontiers in Physics, 2019, 7, .	2.1	22
4	Shadow moire´ profilometry by frequency sweeping. Optical Engineering, 2001, 40, 1383.	1.0	19
5	Measurement of characteristics of magnetic fluid by the Mueller matrix imaging polarimeter. Optical Engineering, 2004, 43, 181.	1.0	15
6	Measurement of Wavelength Dependence of Electro-Optic Coefficients r 22 of Non-doped and 5% MgO-doped Congruent LiNbO3 Crystals and 1.8% MgO-doped Quasi-stoichiometric LiNbO3 Crystal by Multiple Reflection Interference Method. Optical Review, 2007, 14, 194-200.	2.0	15
7	Polarization properties of scattered light from macrorough surfaces. Optics Letters, 2010, 35, 595.	3.3	13
8	Rotatable Offner imaging system for ellipsometric measurement. Review of Scientific Instruments, 2017, 88, 013704.	1.3	11
9	Measurement of diameter of cylindrical openings using a disk beam probe. Optical Review, 2018, 25, 656-662.	2.0	11
10	Copper deposition in microporous silicon using supercritical fluid. Thin Solid Films, 2014, 567, 82-86.	1.8	10
11	In situ imaging ellipsometer using a LiNbO3 electrooptic crystal. Thin Solid Films, 2014, 571, 532-537.	1.8	10
12	Extracting calibrated parameters from imaging ellipsometric measurement. Japanese Journal of Applied Physics, 2017, 56, 116602.	1.5	10
13	Fast and Simultaneous Measurement of Both Birefringence and Azimuth Angle Using ay-Cut LiNbO3Phase Modulator. Japanese Journal of Applied Physics, 2006, 45, 5244-5247.	1.5	9
14	Direct Electropolymerization of Poly(para-phenylene)vinylene Films on Si and Porous Si. Journal of the Electrochemical Society, 2010, 157, H534.	2.9	7
15	Fast Imaging Ellipsometer Using a LiNbO3Electrooptic Crystal. Japanese Journal of Applied Physics, 2013, 52, 036702.	1.5	7
16	Supercritical fluid deposition of copper into mesoporous silicon. Thin Solid Films, 2013, 545, 357-360.	1.8	7
17	General window correction method for ellipsometry measurements. Optics Express, 2014, 22, 27811.	3.4	7
18	Temperature characteristics of a Y-cut Z-propagation LiNbO3 light modulator for application to polarimeters. Optical Review, 2010, 17, 30-40.	2.0	6

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19	Electro-optic modulation analysis of a Y-cut Z-propagation LiNbO3 light modulator: Comparison with an X-cut Z-propagation LiNbO3 light modulator and a dual LiNbO3 crystal type modulator. Optical Review, 2011, 18, 203-211.	2.0	6
20	Polarization characteristics of scattered light from macroscopically rough surfaces. Optical Review, 2015, 22, 511-520.	2.0	6
21	In situ ellipsometry of Cu surfaces immersed in benzotriazole–hydrogen peroxide solutions. Japanese Journal of Applied Physics, 2016, 55, 06JG03.	1.5	6
22	Measurement of Optical Constants of Wet Porous Silicon Using In Situ Photoconduction. ECS Journal of Solid State Science and Technology, 2016, 5, P190-P196.	1.8	6
23	Multi-Wavelength Mueller Matrix Polarimeter. Optical Review, 2005, 12, 281-286.	2.0	5
24	Lateral ellipsometry resolution for imaging ellipsometry measurement. Japanese Journal of Applied Physics, 2021, 60, 058003.	1.5	5
25	Calibration of the retardation inhomogeneity for the compensator-rotating imaging ellipsometer. Applied Optics, 2019, 58, 9224.	1.8	5
26	<i>In-situ</i> Spectroscopic Ellipsometry of the Cu Deposition Process from Supercritical Fluids: Evidence of an Abnormal Surface Layer Formation. Japanese Journal of Applied Physics, 2012, 51, 05EA02.	1.5	5
27	Stokes parameters of reflected and scattered light by a rough surface. Proceedings of SPIE, 2009, , .	0.8	4
28	Electropolymerization of Poly(para-phenylene)vinylene Films onto and Inside Porous Si layers of Different Types and Morphologies. Journal of the Electrochemical Society, 2010, 157, D648.	2.9	4
29	Electro-Optic Coefficient r <sub>51</sub> of LiNbO <sub>3</sub> Crystal Obtained from Measurement of Retardation Induced by Square of Electric Field. Japanese Journal of Applied Physics, 2013, 52, 058001.	1.5	4
30	Correction of large birefringent effect of windows for in situ ellipsometry measurements. Optics Letters, 2014, 39, 1549.	3.3	4
31	Correction of large retardation window effect for ellipsometry measurements using quasi-Newton method. Applied Optics, 2015, 54, 2991.	1.8	4
32	Dispersion measurement of the electro-optic coefficientr22of the LiNbO3crystal with Mueller matrix spectropolarimetry. Japanese Journal of Applied Physics, 2015, 54, 078003.	1.5	4
33	Selective Cu filling of nanopores using supercritical carbon dioxide. Japanese Journal of Applied Physics, 2015, 54, 05EA02.	1.5	4
34	In-situ Spectroscopic Ellipsometry of the Cu Deposition Process from Supercritical Fluids: Evidence of an Abnormal Surface Layer Formation. Japanese Journal of Applied Physics, 2012, 51, 05EA02.	1.5	3
35	In situ observation of Pt deposition process by using spectroscopic ellipsometry. Microelectronic Engineering, 2014, 121, 39-41.	2.4	3
36	Polarization characteristics of diffraction scattering from metal rough surface. Applied Surface Science, 2017, 421, 565-570.	6.1	3

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37	Optical Absorption and Quantum Confinement in Porous Silicon Nanostructures Studied by Chemical Dissolution in HF Solutions and Photoconduction. ECS Journal of Solid State Science and Technology, 2017, 6, R1-R6.	1.8	3
38	Structures of Cu surfaces developing in benzotriazole solutions: Effect of pH. Japanese Journal of Applied Physics, 2017, 56, 07KH01.	1.5	3
39	Imaging ellipsometry measurement noises associated with non-uniform retardation of the compensator. Optical Review, 2020, 27, 73-80.	2.0	3
40	Image detection system for 157-nm using fluorescent glass. , 2003, , .		2
41	Birefringence Polarimeter Using Dual LiNbO\$_{3}\$ Electrooptic Crystal Modulators. Japanese Journal of Applied Physics, 2012, 51, 082201.	1.5	2
42	Extraction of polarization properties of the individual components of a layered system by using spectroscopic Mueller matrix analysis. Optics Express, 2016, 24, 9757.	3.4	2
43	Removal of organic template of mesoporous organosilicate thin films using supercritical carbon dioxide fluids. Japanese Journal of Applied Physics, 2017, 56, 07KF02.	1.5	2
44	Photoetching of Porous Silicon Nanostructures in Hydrofluoric Acid Using Monochromatic Light. ECS Journal of Solid State Science and Technology, 2018, 7, P730-P735.	1.8	2
45	Flat-shaped microfluidic optical cell for in situ ellipsometry using glass slide as optical window component. Japanese Journal of Applied Physics, 2018, 57, 07MD01.	1.5	2
46	Mueller matrix polarimeter in 157nm. , 2003, 5188, 146.		1
47	Effect of Multiple Reflections on Accuracy of Electro-Optic Coefficient Measurements. Japanese Journal of Applied Physics, 2007, 46, 7904-7911.	1.5	1
48	Tunable electro-optic crystal Fabry-Perot filter. Proceedings of SPIE, 2010, , .	0.8	1
49	Polarization analysis of scattering light using a facet model. Proceedings of SPIE, 2011, , .	0.8	1
50	Facile and Efficient Gas-Phase Pressure-Controlled Thermal Functionalization of Nanocrystalline Porous Silicon with 1-Hexene. ECS Journal of Solid State Science and Technology, 2019, 8, R109-R113.	1.8	1
51	Moire Metrology. , 2009, , .		1
52	Publisher's Note: "Birefringence Polarimeter Using Dual LiNbO\$_{3}\$ Electrooptic Crystal Modulators― Japanese Journal of Applied Physics, 0, 51, 089202.	1.5	1
53	Characterization of thin films from reflection and transmission ellipsometric parameters. Japanese Journal of Applied Physics, 2022, 61, 018004.	1.5	1
54	<title>Shadow moire profilometry using a phase-shifting method</title> . , 1999, 3740, 110.		0

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55	Measurement of characteristics of magnetic fluid by Mueller matrix imaging polarimeter. , 2002, 4919, 183.		0
56	Two-dimensional birefringence measurement using liquid crystal retarder for plastic disk inspection. , 2002, , .		0
57	Development of television camera for detecting oil film floating on the ocean. , 2006, , .		0
58	Performance of a television camera system for the detection of oil slicks. Optical Engineering, 2008, 47, 093801.	1.0	0
59	(Invited) Electropolymerized Poly(para-phenylene)vinylene Films onto and Inside Porous Si. ECS Transactions, 2010, 28, 91-103.	0.5	0
60	Analysis of the quadratic retardation induced by the Pockels, Kerr, and inverse piezoelectric effects in anX-cutY-propagation LiNbO3. Japanese Journal of Applied Physics, 2014, 53, 052601.	1.5	0
61	(Invited) Porous Silicon Dissolution Monitoring and Optical Constants Measurement Using in Situ Photoconduction in HF. ECS Transactions, 2016, 75, 63-75.	0.5	0
62	(Invited) Photo-Assisted Etching of Porous Silicon Nanostructures in Hydrofluoric Acid Using Monochromatic Light. ECS Transactions, 2018, 86, 71-81.	0.5	0
63	Birefringence Polarimeter Using Dual LiNbO <sub>3</sub> Electrooptic Crystal Modulators. Japanese Journal of Applied Physics, 2012, 51, 082201.	1.5	0
64	Extraction of properties of individual component for the retarder-linear diattenuator-retarder system and its application. , 2018, , .		0
65	Dimensional measurement of internal profile using the optical caliper. , 2018, , .		0
66	Design of a spectroscopic imaging ellipsometer. , 2020, , .		0
67	Hydrosilylation of High Porosity Porous Silicon with 1-Hexene in Supercritical CO2 Fluid. ECS Journal of Solid State Science and Technology, 0, , .	1.8	0
68	3D profile measurement of openings with optical caliper. , 2021, , .		0
69	Ellipsometric Microscope ―Design and Application of a Microscope for Oblique Observation of Samples―. Journal of the Japan Society for Precision Engineering, 2020, 86, 533-536.	0.1	0
70	Optical profilometry of cylindrical openings for transparent objects. , 2020, , .		0
71	High Energy Limit of the Size-Tunable Photoluminescence of Hydrogen-Terminated Porous Silicon Nanostructures in HF. ECS Journal of Solid State Science and Technology, 0, , .	1.8	0
72	Electron Escape from Filled Band in Wet Porous Silicon Nanostructure Probed by Luminescence Quenching Dynamics. ECS Journal of Solid State Science and Technology, 0, , .	1.8	0